



Vacuum Cassette Load Ports

Robotic Components

	ALP-200	CLP-200	MLP-200
Wafer Sizes	≤200mm*		
Pay Load	34 Kg†		
Axis of motion	Z	Z	N/A
Transfer Height	1100mm		
High Vacuum Configuration	N/A	Available	
Vacuum performance			
Base operating pressure	N/A	<5.00E-06 Torr	<5.00E-06 Torr
Leak Rate	N/A	1.00E-09 scc He/sec	1.00E-09 scc He/sec
Input Power	24VDC @ 5 Amps		
Cassette type	SEMI Standard Cassettes (≤200mm)		Custom 4 wafer cassette
Materials Exposed	6061-T6 Aluminum, Stainless Steel 300 and 400 Series, Viton, Borosilicate Glass		
Mounting	200mm MESC Slit Valve Support Frame as Required		
Max. Operating Temperature	100°C		
Repeatability			
Vertical Travel	0.10mm **		N/A
Speed			
Vertical Travel	185mm		N/A
Cassette Mapping time	10 seconds		N/A
MTBF	>3.00E+06		N/A

* Hine Automation offers cassette cradle for SEMI standard sizes up to 200mm. Other sizes are available upon request.

† Payload with standard configuration

** Measured as three standard deviations (3σ)